

## UPCOMING EVENTS

### PhD defense Rosalia Delgado Carrascon:

*“Epitaxy of group III-nitride materials using different nucleation schemes”*

10:00 – Friday 9<sup>th</sup> of June 2023, LiU

### Master defense Andri Dhora:

*“Thick GaN and AlGaIn drift layer development for efficient power conversion”*

10:00 – Monday 21<sup>st</sup> of August 2023, LU

## PUBLICATIONS

**EDITOR’S PICK:** A. Papamichail, et al., *“Tuning composition in graded AlGaIn channel HEMTs toward improved linearity for low-noise radio-frequency amplifiers”*, Appl. Phys. Lett. **122**, 153501 (2023). [link](#)

H. Zhang, et al., *“Polarity Control by Inversion Domain Suppression in N-Polar III-Nitride Heterostructures”*, Crystal Growth & Design **23** (2), 1049 (2023). [link](#)

P. Gribisch, et al., *“Tuning of Quasi-Vertical GaN FinFETs Fabricated on SiC Substrates”*, IEEE T. Electron Dev. **70** (5), 2408 (2023). [link](#)

D. Q. Tran, et al., *“Thermal conductivity of Sc<sub>x</sub>Al<sub>1-x</sub>N and Y<sub>x</sub>Al<sub>1-x</sub>N alloys”*, Appl. Phys. Lett. **122** (18), 182107 (2023). [link](#)

H. Zhang, et al., *“High quality N-polar GaN optimization by multi-temperature growth process”*, J. Cryst. Growth **607**, 127002 (2023). [link](#)

## New projects

**WISE Post Doc, LiU** – AlN material platform for efficient power switching and conversion

**WISE Ind Post Doc, Hexagem and LU** – High performance WBG power electronics at Si cost

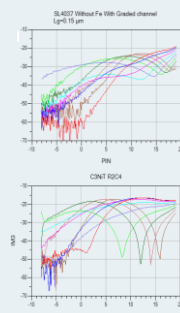
**WISE Ind PhD student, Veeco and LU** – Next generation high power gallium oxide material for an energy efficient smart grid

## PROJECT UPDATES



### Linear E/W band HEMTs and MMICs

The first large signal measurements in Europe of a graded channel AlGaIn/GaN HEMT has been carried out by the industrial PhD student Andreas Divinyi. The linearity figure of merit IM3 was improved by 10 dB compared to a conventional Fe-doped GaN buffer. These results are showing state of the art performance and paves the way for novel highly linear GaN receivers.



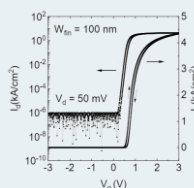
### High voltage HEMTs and circuits for power and microwave applications

Sc<sub>x</sub>Al<sub>1-x</sub>N/GaN HEMTs are promising structures for increased power density compared to Al<sub>x</sub>Ga<sub>1-x</sub>N/GaN HEMTs. Critical progress has been made by studying the thermal conductivity of the Sc<sub>x</sub>Al<sub>1-x</sub>N alloy. Preliminary results report k=6.2 W/mK and k=3.2W/mK for the compositions x=0.14 and x=0.41, respectively, and for the layer thickness of 1 μm.



### Vertical devices for power application

We have successfully build our first vertical GaN on GaN FinFET transistors, showing normally off behaviour with VT around 0.7V. The device shows excellent performance, with state-of-the-art effective mobility of 160 cm<sup>2</sup>/(Vs) and ideal inverse subthreshold slopes of 60 mV/decade, at a breakdown voltage of 90V. 650-1200V breakdown voltages are the next goal!



### Propulsion/Charger/Converter/Switching applications

C3NiT Volvo Industrial Ph.D. Student Pengpeng Sun has started his research in the area of nonlinear GaN transistor models suitable for the prediction of switching waveforms and losses in power electronic applications. For the initial work, commercially available transistors have been purchased, mounted, and tested through initial DC measurements. Our next step will be to extend the experiments to pulsed dc and high-frequency characterization, which will form the foundation for the modeling work ahead.



### Advanced epitaxial concepts for cost reduction

AlGaIn/GaN high electron mobility transistors (HEMTs) with high-Al-content ultrathin barrier layers were developed for ultra-high working frequency applications. Control of the thickness and the composition of thin Al<sub>x</sub>Ga<sub>1-x</sub>N (x= 0.50-0.60) barrier layers is achieved while the HEMT structures were tested for aging with no signs of actual degradation.

State-of-the-art 10 μm GaN and 5 μm AlGaIn drift layers with controlled doping and strain engineering have been developed by MOCVD and are currently used for FinFET device fabrication.

Next Board Meeting June 15<sup>th</sup> 2023 via Teams